

	Type	Ref #	Hits	Search Text	DBs
4	BRS	S17	1049	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and magnet and coil	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
5	BRS	S18	4549	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) same substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
6	BRS	S19	149	((microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) same substrate) same transistor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
7	BRS	S20	17	((microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) same substrate) same transistor same array	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
8	BRS	S21	634	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) same transistor	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
9	BRS	S22	85	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) same transistor same array	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
10	BRS	S23	36973	microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
11	BRS	S24	9	("5121089" "6040748" "6046659" "6115231").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
12	BRS	S25	808	335/78.ccls. 200/181.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Type	Ref #	Hits	Search Text	DBs
13	BRS	S26	38810	microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
14	BRS	S28	178	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
15	BRS	S38	38810	microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
16	BRS	S39	18	333/101.ccls. and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
17	BRS	S50	935	335/78.ccls. 200/181.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
18	BRS	S51	1771	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and magnet and coil	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
19	BRS	S52	264	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
20	BRS	S53	26	333/101.ccls. and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
21	BRS	S54	105	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and magnet\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Type	Ref #	Hits	Search Text	DBs
22	BRS	S55	174	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and dielectric	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
23	BRS	S56	169	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and dielectric and substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
24	BRS	S57	138005	dielectric same (silicon oxygen nitrogen si o n)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
25	BRS	S58	96276	dielectric with (silicon oxygen nitrogen si o n)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
26	BRS	S59	60	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and substrate and S58	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
27	BRS	S60	119	(335/78.ccls. 200/181.ccls.) and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and cantilever and dielectric	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
28	IS&R	S61	2	("6768403").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
29	BRS	S62	14288	silicon adj oxynitride	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Type	Ref #	Hits	Search Text	DBs
30	BRS	S63	4544	S62 with dielectric	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
31	BRS	S64	129	S63 and (microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
32	BRS	S65	17636	pecvd ("plasma enhanced chemical vapor deposition")	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
33	BRS	S66	1282	S63 and S65	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
34	BRS	S67	381	S63 same S65	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
35	BRS	S68	27748	Sion (silicon adj oxynitride)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
36	BRS	S69	5471	S68 with dielectric	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
37	BRS	S70	230	S69 with S65	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
38	BRS	S71	1	S70 and cantilever	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
39	BRS	S72	0	("2005/0088261").URPN.	USPAT
40	BRS	S73	1	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator) and S70	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Type	Ref #	Hits	Search Text	DBs
41	BRS	S74	1378	S65 same S68	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
42	BRS	S75	71	S74 and "240" and degrees	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
43	BRS	S76	1	S74 and "240" adj degrees	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
44	BRS	S77	1	("2001/0044220").URPN.	USPAT
45	BRS	S78	7	("20010044220" "4543707" "5880018" "6060132" "6153541" "6221794" "6294460").PN. OR ("6410461").URPN.	US-PGPUB; USPAT; USOCR
46	BRS	S79	270	(silane sih4 ("SiH. ₄ ")) with ("nitrous oxide" n2o("N. ₂ O")) with (nitrogen n2 ("N. ₂ ")) with (NH3 ("NH. ₃ "))	US-PGPUB; USPAT; USOCR
47	BRS	S80	142	S62 and S79	US-PGPUB; USPAT; USOCR
48	BRS	S81	6	("5578976" "6046659" "610047 7").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
49	BRS	S82	701	form same dielectric same ("200" "300") same degrees	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
50	BRS	S83	54918	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
51	BRS	S84	69	S82 and S83	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB
52	BRS	S85	54918	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or mems or microactuator)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM TDB

	Type	Ref #	Hits	Search Text	DBs
53	BRS	S86	69	S82 and S85	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB